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Epitaxial refractory-metal buffer layers with a chemical gradient for adjustable lattice parameter and controlled chemical interface

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We have developed and characterized the structure and composition of nanometers-thick solid-solution epitaxial layers of (V,Nb) on sapphire (1120), displaying a continuous lateral gradient of composition from one to another pure element. Further covered with an ultrathin pseudomorphic layer of W, these provide a template for the fast combinatorial investigation of any growth or physical property depending of strain.

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Thin films play a crucial role in integrated technology, 52 14 and it is necessary to control their physical properties. 53 15 In a down-scaling approach one seeks to sustain the bulk 54 16 properties. One may also endeavor to tailor new proper- 55 17 ties that do not occur in the bulk, an approach being one 56 18 basis for the development of nanosciences. The parame- 57 19 ter often at play in the change of properties in thin films is $_{58}$ 20 strain¹, influencing *e.g.* mobility in semiconductors², op- ⁵⁹ 21 tical activity, electric polarization or magnetic moment³ 60 22 and anisotropy⁴. The easiest way to control strain in thin 61 23 film is through their epitaxy on substrates with a lattice 62 24 parameter different from their own, inducing a so-called 63 25 lattice misfit. Lattice misfit also influences growth modes $_{64}$ 26 (smooth or rough films, islands...)^{5,6}, which strengthens $\frac{1}{65}$ 27 the need for its control. 28 66

Effects of lattice misfit are often investigated by growth 67 29 on single crystals of various pure elements, each with 68 30 a well-defined lattice parameter. Alloys and solid solu- 69 31 tions (s.s.) are an appealing combinatorial alternative 70 32 as they allow for the continuous control of lattice misfit, 71 33 which is not possible for pure elements⁷. Nevertheless, 72 34 systematic studies with s.s. require several samples with 73 35 different compositions, with issues of time, reproducibil-74 36 ity and limited number of data points. To circumvent this 75 37 Kennedy et al.⁸ have introduced compositional spreads, 76 38 where the anisotropy of evaporation of two sources are 77 39 used to create a slight gradient of composition across 78 40 a sample. Later, alternated deposition of the materials 79 41 along with moving masks were used to create intercalated ⁸⁰ 42 wedges of two or three elements^{9,10}. This allows one to ⁸¹ 43 vary the composition linearly and potentially from 0% 82 44 up to 100%. In these seminal uses of masks the alloy $_{\rm 83}$ 45 resulted from a post-annealing, which is not suited for 84 46 most epitaxial and thin films. Only Zhong et al. applied 85 47 this technique to epitaxial materials (semiconductors), 86 48 however restricted it to the case of weak doping¹¹. 87 49

⁵⁰ We issued a preliminary report of chemical gradients ⁸⁸ ⁵¹ with controlled chemical surface¹², however with a neg- ⁸⁹ ligible variation of lattice parameter via mixing bodycentered cubic (bcc) Mo (lattice parameter 3.157 Å) and W (3.165 Å), therefore with virtually no metallurgical issues and with restricted practical use. Here we report the fabrication, the structural, composition and surface characterization of epitaxial Chemical-Gradient Layers (CGLs) of bcc refractory metals, in the full range of composition to adjust the lattice parameter over 10 %. Further combined with an ultrathin pseudomorphic layer, these provide a versatile buffer-layer toolkit for the elucidation and use of the many phenomena depending on lattice mismatch.

The samples were grown using Pulsed-Laser Deposition in a set of Ultra-High-Vacuum chambers. The laser is a 10 Hz-pulsed Nd-YAG laser with pulse length ≈ 10 ns and doubled frequency ($\lambda = 532 \,\mathrm{nm}$). The deposition chamber is equipped with a computer-controlled mask moving in front of the sample, and 10 kV Reflection High Energy Electron Diffraction (RHEED)¹². Our CGLs are based on mixtures of two bcc elements (Mo, W, Nb, V), that all form s.s. one with another. Results are illustrated in this Letter with the case of (V,Nb). $(11\overline{2}0)$ sapphire wafers are used as a support, resulting in the (110) texture of the films^{12,13}. Searching for an optimized procedure, CGLs were grown directly on 0.7 nm-thick-Mo-dusted sapphire wafer (Mo is inserted to avoid crystallographic variants¹²), or on an atomically-flat 10 nmthick W(110) buffer layer itself above Mo-dusted sapphire. The wedges of the two elements are deposited sequentially, in an opposite fashion thanks to the azimuthal rotation of the sample of 180°. The length of the wedges is 5 mm (FIG. 1a). Their typical thickness is 1 Å, which is less than one atomic layer, with a view to promote the mixture of both elements at the atomic level and avoid the formation of misfit dislocations that would occur for thick individual layers. Deposition is performed at moderate temperature $(300 \,^{\circ}\text{C})$, followed by annealing for 30 min at 800 °C to smoothen the surface. The typical total thickness of these films is 10 nm.

FIG. 1 shows RHEED patterns and Scanning Tunneling Microscopy (STM) images of a (V,Nb)/Mo(0.7 nm) CGL directly grown on sapphire. The RHEED streak

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FIG. 1. (a) Schematics of a CGL, further covered by an ultrathin W layer for the chemical control of the free surface. (b) typical RHEED pattern, for electron azimuth [110] (the bright spot is the reflected beam). STM images of $(V,Nb)/Mo(0.7 \text{ nm})/Al_2O_3$ CGLs (not covered with an ultrathin W layer) for (c) V, (d) V₅₀Nb₅₀ and (e) Nb .

narrowness, large terrace size and absence of emerging
screw dislocations, provide a picture of a high-quality
crystal. No significant difference is found in RHEED and
STM data as a function of the local composition, from
pure V to pure Nb, with or without an underlying W
buffer layer.

We developed a sample holder to perform X-Ray 7 Diffraction over a small and precise location on the 33 8 sample. It consists of a 1 mm-wide window between ³⁴ 9 two steel blades machined at an angle of 12° to let ³⁵ 10 in and out X-rays down to grazing incidence. The 36 11 blades are covered with a $10\,\mu\text{m}$ -thick layer of metallic ³⁷ 12 glass (Zr_{52.5}Ti_{2.5}Cu₂₂Ni₁₃Al₁₀) to avoid diffraction from ³⁸ 13 the mask. A manual sample translator allows one to se- 39 14 lect the area of investigation (inset of FIG. 2a). FIG. 2a 40 15 shows $\theta - 2\theta$ spectra as a function of location on the sam- 41 16 ple, translated into the expected composition. The oc- 42 17 currence of Kiessig fringes arises from the finite thickness 43 18 of the films and the absence of roughness. Their width 44 19 is composition-independent and consistent with the film 45 20 thickness. The films are thus coherent across their entire 46 21 thickness, showing their good layered structure, consis- 47 22 tent with STM data (FIG. 1c-e). The out-of-plane lat- 48 23 tice parameters extracted from these curves are shown 49 24 in FIG. 2b. The error bars result from the precision of $_{50}$ 25 the lateral position of the sample, and from the com- 51 26 bined fitting of peaks and calibration of the diffractome- 52 27 ter against the first and second order peaks of sapphire. 53 28 Within the error bar the lattice parameter varies linearly 54 29 with composition and ranges from the bulk lattice pa- 55 30 rameter of V (3.02 Å) to that of Nb (3.30 Å), in agree- 56 31 ment with Vegard's Law. in situ RHEED yields the in- 57 32



FIG. 2. (a) $\theta - 2\theta$ diffraction spectra of $(V,Nb)/Mo(0.7 \text{ nm})/Al_2O_3$ CGLs. At 37.85° is a sapphire peak. Inset: mask used to select the area of interest for diffraction (b) Extracted from (a), out-of-plane lattice parameter as a function of composition along the CGL. Lines are the expectation of Vegard's law. STM images of ultrathin layers of W of thickness (c) 0.6 nm and (d) 2 nm on a CGL.

plane lattice parameter, albeit with larger error bars (not shown here). These also fit Vegard's law, demonstrating the good structural relaxation of the s.s.. Finally, the CGLs may be covered by an ultrathin W layer deposited at 250 °C and then annealed at 800 °C, a procedure known not to give rise to intermixing with the underlying film¹². STM shows that W remains pseudomorphic up to ≈ 1 nm (FIG. 2c), above which relaxation is revealed by an array of misfit dislocations (FIG. 2d)¹⁴. CGLs covered with this ultrathin pseudomorphic W layer provide a surface with a continuously-variable lattice parameter, however with a uniform and a rather inert surface material.

In order to check locally both the composition of the s.s., and their crystalline quality, the samples were also analyzed using Rutherford Backscattering Spectrometry (RBS) both in random and channeling geometries (for these analytical techniques, see Ref.¹⁵). Indeed, whereas X-ray and electron diffraction probe long-range crystalline coherence and are mostly insensitive to local disorder, RBS in a channeling geometry is highly sensitive to such disorder and is thus very valuable to refine the close-to-perfect picture of CGLs given by FIG. 1 and 2. RBS was performed within the SAFIR facility of the INSP, using a 1.4 MeV ⁴He⁺ ion beam with a 0.5 mm diameter,



FIG. 3. Local quantities determined by RBS (random or ⁵⁰ channeling conditions), as a function of the location x across ⁵¹ a (V,Nb)/W(10 nm)/Mo(0.7 nm)/Al₂O₃ CGL: Nb concen-⁵² tration (•), normalized channeling ([110] alignment) yields $Y_{\rm Nb}$ (o), $Y_{\rm V}$ (\bigtriangledown) and $Y_{\rm W}$ (\square) (see text). The zero for the lateral scale is different from that of FIG. 2b.

¹ produced by a 2.5 MV Van de Graaff accelerator. The ⁵⁴ ² ions scattered elastically at large angle (here $\approx 150^{\circ}$) on ⁵⁵ ³ the sample nuclei (rare scattering events) were energy- ⁵⁶ ⁴ analyzed using a silicon detector. ⁵⁷

Conversely, the most probable scattering events result 58 5 in small-angle repulsive deflections. When the incident ⁵⁹ 6 beam is aligned with a major crystallographic axis of 60 a crystal (channeling geometry, here performed along 61 8 [110]), these deflections are correlated and the particle 62 ¢ flux close to the rows is strongly reduced, leading to a 10 similar reduction of the RBS yield Y with respect to the 11 yield R using a random orientation of the beam. For $_{63}$ 12 convenience, in the following Y values are normalized to 13 the corresponding RBS random yield. Whereas R_i val-14 ues for element i are proportional to the absolute amount ₆₄ 15 of i atoms in the layer, Y_i values are mostly sensitive to 65

¹⁶ of *i* atoms in the layer, Y_i values are mostly sensitive to ⁶⁵ atomic displacements in the plane perpendicular to the ⁶⁶ ⁶⁷ channeling axis¹⁶.

Various samples were analyzed, but we only present $\frac{1}{69}$ 19 here the case of (V,Nb) deposited on a 10 nm-thick 70 20 W(110) buffer layer (FIG. 3). Both $R_{\rm V}(x)$ and $R_{\rm Nb}(x)$ ⁷¹ 21 exhibit a linear variation across the sample, their sum 72 22 keeping a nearly constant value corresponding to a thick- $\frac{73}{74}$ 23 ness of about 10 nm of the (Nb,V) layer. This provides a $\frac{1}{75}$ 24 direct quantitative confirmation of the linear variation of 76 25 composition [e.g. $C_{\rm Nb} = R_{\rm Nb}/(R_{\rm Nb} + R_{\rm V})$] with x, sug-⁷⁷ 26 gested indirectly previously through the agreement with 78 27 Vegard's Law (FIG. 2). 28

Concerning the crystalline quality of the s.s., the rel- 81 29 atively high channeling yields $Y_{\rm Nb}$ and $Y_{\rm V}$ observed on ⁸² 30 FIG. 3, with a marked dependence on $C_{\rm Nb}$, may hint at ⁸³ 31 atomic displacements in the s.s., relatively far from the $^{\rm 84}$ 32 CGL-W interface (see below). Their precise identifica- $\frac{3}{86}$ 33 tion needs further analysis. Despite this, paradoxically, 87 34 the very low channeling yield $Y_{\rm W}$ in the range [0.02-0.05] ** 35 is indicative of a very good epitaxy. The highest qual-⁸⁹ 36 ity $(Y_{\rm W} \approx 0.02)$ is obtained for Nb_{0.5}V_{0.5}, for which there $\frac{90}{91}$ 37 is no lattice mismatch between the alloy and W, in agree- $\frac{1}{92}$ 38 ment with FIG. 2b. 39 93

40 To conclude, we developed high-quality epitaxial solid- 94

solution layers of refractory metals along the orientation (110), in the form of Chemical-Gradient Layers (CGLs). These CGLs were then covered with a flat and ultrathin pseudomorphic layer of W(110). This combination provides a template with a lattice parameter varying laterally over 10 % and with a controlled and rather inert W chemical interface, which may be used for the fast combinatorial investigation of any growth or physical phenomenon depending on strain. This may be performed with local probes such as electron, optical or scanning-probe microscopies, or with many nowadays synchrotrons offering beams focused to 100 μ m or smaller.

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- ¹⁶A detailed discussion of RBS-channeling data will be addressed separately.